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Fourth European Seminar on Precision Optics Manufacturing

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Editors

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Introduction

The Fourth European Seminar on Precision Optics Manufacturing took place in Teisnach, Germany, from 4–5 April 2017. Over 120 attendees from all over the world met to discuss topics surrounding manufacturing and measuring technology for precision optics and optical systems. In cooperation with SPIE, this conference became the biggest symposium on optics manufacturing in the German area. The organizers, Deggendorf Institute of Technology (Germany) and the Technology Campus Teisnach (Germany), express their thanks to our committee members, conference and session chairs, all the authors and speakers, and to the internal team behind the scenes. Their contributions of time and effort were the basis of the symposium's great success. We also thank SPIE staff, who did everything correctly, on time, and in a professional way. Such a symposium is brought to life by the audience. Thanks to all the attendees who listened to the talks and gave feedback. The lively and intense discussions during the breaks and sessions indicate the need for a high-level communication platform for the experts in optics manufacturing technologies. Papers addressed a wide range of current tasks in industry and research and covered these main topics:

- Manufacturing and measurement of high precision elements, large optics, and optical systems
- Surface modification, cleaning and coating of optics
- Advanced technologies in high precision manufacturing
- Industry 4.0 in environment, media control, process stability and data handling

The presented contributions and discussions confirmed the high industrial relevance of the symposium. In these proceedings, the reader will find a great number of the presented talks and posters presented during the symposium.

We look forward to continuing this series of symposia with the Fifth European Seminar on Precision Optics Manufacturing on 10 – 11 April 2018. Papers will be accepted until 31 December 2017.

Rolf Rascher
Oliver W. Föhnle
Christine Wünsche
Christian Schopf

